

Scientific Motivation And Necessity of Cathode Development

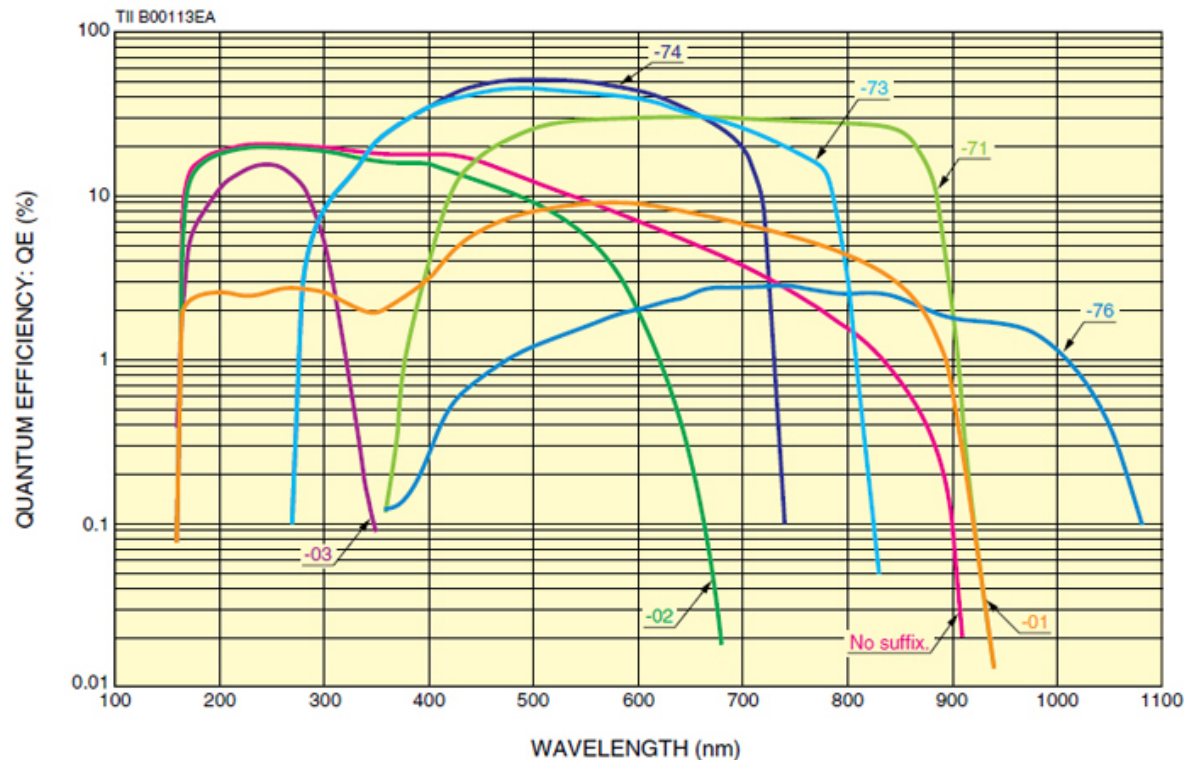
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* Speakers of the review

The Photocathode Families

Hamamatsu: http://jp.hamamatsu.com/products/sensor-etc/pd014/index_en.html



| Suffix | Photocathode | Input Window |
|--------|--------------------------|--------------------|
| -71 | GaAs | Borosilicate Glass |
| -73 | Enhanced Red GaAsP | Borosilicate Glass |
| -74 | GaAsP | Borosilicate Glass |
| -76 | InGaAs | Borosilicate Glass |
| Non | Multialkali | Synthetic Silica |
| -01 | Enhanced Red Multialkali | Synthetic Silica |
| -02 | Bialkali | Synthetic Silica |
| -03 | Cs-Te | Synthetic Silica |

- Required spectral response still not clear (main application)
- Future applications (combination with scintillators) will require response optimization

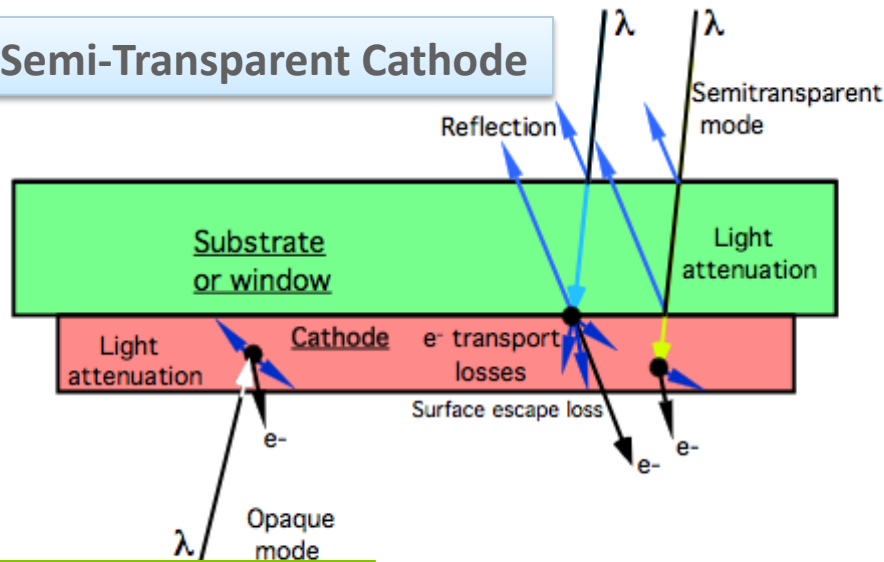
Why are we Planning a Large Cathode Effort?

- Multi-Alkali seems to have perfect cathode properties
- But
 - Little understanding
 - Small community
 - No developed Industry
 - **Problems with mass-production**
- Existing III-V cathode have not the right properties
- But
 - Excellent understanding
 - Large community
 - Excellent developed Industry
 - Easy mass-production

| | Property | Multi-Alkali | GaAs-based | GaN-based |
|-------------------------|-------------------------------------|--|---------------------------|---------------------------|
| Photocathode Properties | Wavelength response (typical) | 150nm-500nm | 450nm-850nm | 100nm-350nm |
| | Typical efficiency | 20% | 20% | 30-40% |
| | Maximum efficiency | 50% | 60% | 80% |
| | Wavelength tunability | low | large | Very high |
| | Dark current | ~100cps/cm2 | ~10000cps/cm2 | ~100cps/cm2 |
| Growth properties | Single crystal substrate | no | yes | yes |
| | Easy scalable | No | yes | yes |
| | Large production volume possible | No | Yes | Yes |
| | Prefabrication possible | No | Yes | Yes |
| | Temperature sensitive | High | Medium | Medium |
| | Existing Industry | No (besides night vision / small area) | Yes (foundries available) | Yes (foundries available) |
| Basic Physics | Good understanding | No | Yes | Yes |
| | Microscopic understanding of growth | No | Yes | Yes |
| | 2-D Fabrication tools | No | Yes | Yes |
| | 3-D Fabrication tools | No | Yes | Some |
| | Theoretical description | No | Yes | Yes |
| | Band-structure engineering | No | Yes | Yes |

What has to be Optimized?

Semi-Transparent Cathode



Opaque Cathode

The optimization Problem

- Optical Losses (ST-Cathode):
 - Entrance window
 - Interface window/cathode
 - Transmission losses (non absorbed photon)
- Optical Losses (Opaque-Cathode):
 - Vacuum-cathode surface
 - Transmission losses
- Electronic Losses:
 - Random walk results in maximal 50% efficiency
 - Recombination losses (highly correlated with defects)
 - Surface escape losses

The engineering Problem

- Cost efficient production
- Large variation in production volume
- Production compatibility with the full detection system

Detector properties

- Dark current
- Ion-bombardment (lifetime issues)
- Vacuum requirement of detection system
- In vacuum/inert gas assembly

Godparent Review: PC Activity at ANL



The Challenges

Specifics to the Large Area Photo Detector Project:

- Extreme large production variation will require:
 - Fast production of individual components
 - Storage of individual subcomponents
 - Minimizing of production line “size” which can only be used for the detection system
 - Production cannot be done in piece-by-piece production
- Large area of detector:
 - Homogeneity requirements
 - Large facilities -> long production cycle (at least for piece-by-piece production)
 - Production yield problems?
 - Unusual shape (square) require specific tooling for usage of industrial instrumentation
- Low dark current:

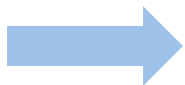
The Challenges:

The Cathode and the Rest of the Detector

- Photocathode is the most sensitive part of the detector: None of the following properties can be changed after activation (without loss of QE)
 - Surface morphology
 - Chemical composition of surface & bulk
 - Structural composition of surface & bulk



- Strong requirements on assembly and sealing technology
 - Maximal temperature and time in which the cathode is exposed to heat
 - Surface contamination due to degassing during the sealing process
 - Vacuum/inert gas requirements determine cost of the production



Research has to focus not only on high QE and low dark current but also on production related problems

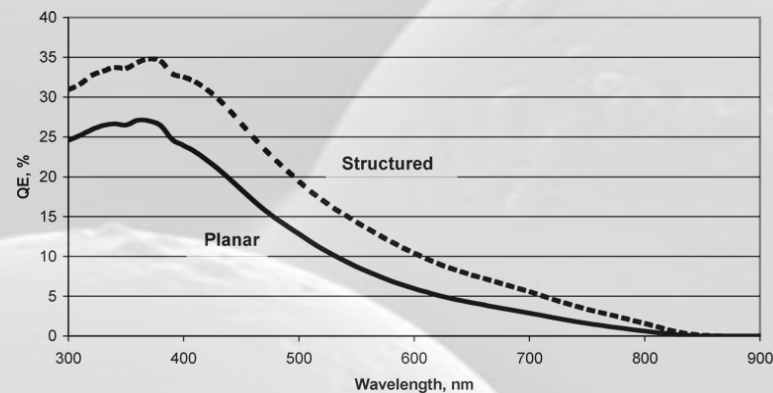
The Approach

- The three different aspects:
 - Basic physics, growth aspects, optics: small size sample (10x10mm²)
 - Full functionality system test: 33mm diameter
 - 8"x8" issues: full size cathode
- Required infrastructure:
 - “Small” chamber size compatible with “lab” –size standard characterization
 - Cost efficient use of substrates
 - Cost efficient chamber design (cryostats/transfer systems)
 - Fast turnover (pumping down....)
 - Large throughput for characterization
 - System can produce also the 33mm diameter system with limited characterization option
 - Large flexible chamber
 - Minimum characterization
 - Ex-situ characterization
 - Development of evaporators, heaters..... (engineering problems)
 - Minimizing efforts on infrastructure
 - Using external collaboration partners

The Challenges: The Multi-Alkali

The Advantages:

- Perfect frequency response
- Very low dark current properties
- Moderate QE is standard (~20%)
- Recipes are available for small area & relative “low production volume”



The Challenges:

- Potentially much higher QE possible (up to 60%)
- Most optimization was achieved by optimizing window/cathode interface (optical and electronic influence)
- Alkali evaporation is an equilibrium problem (adsorption/desorption) making controlled coating technologies very difficult
- Significant engineering effort (constant temperature of cathode) is necessary to scale up to large size and high production volume
- High sensitivity of cathode to gases and temperature makes the sealing more challenging

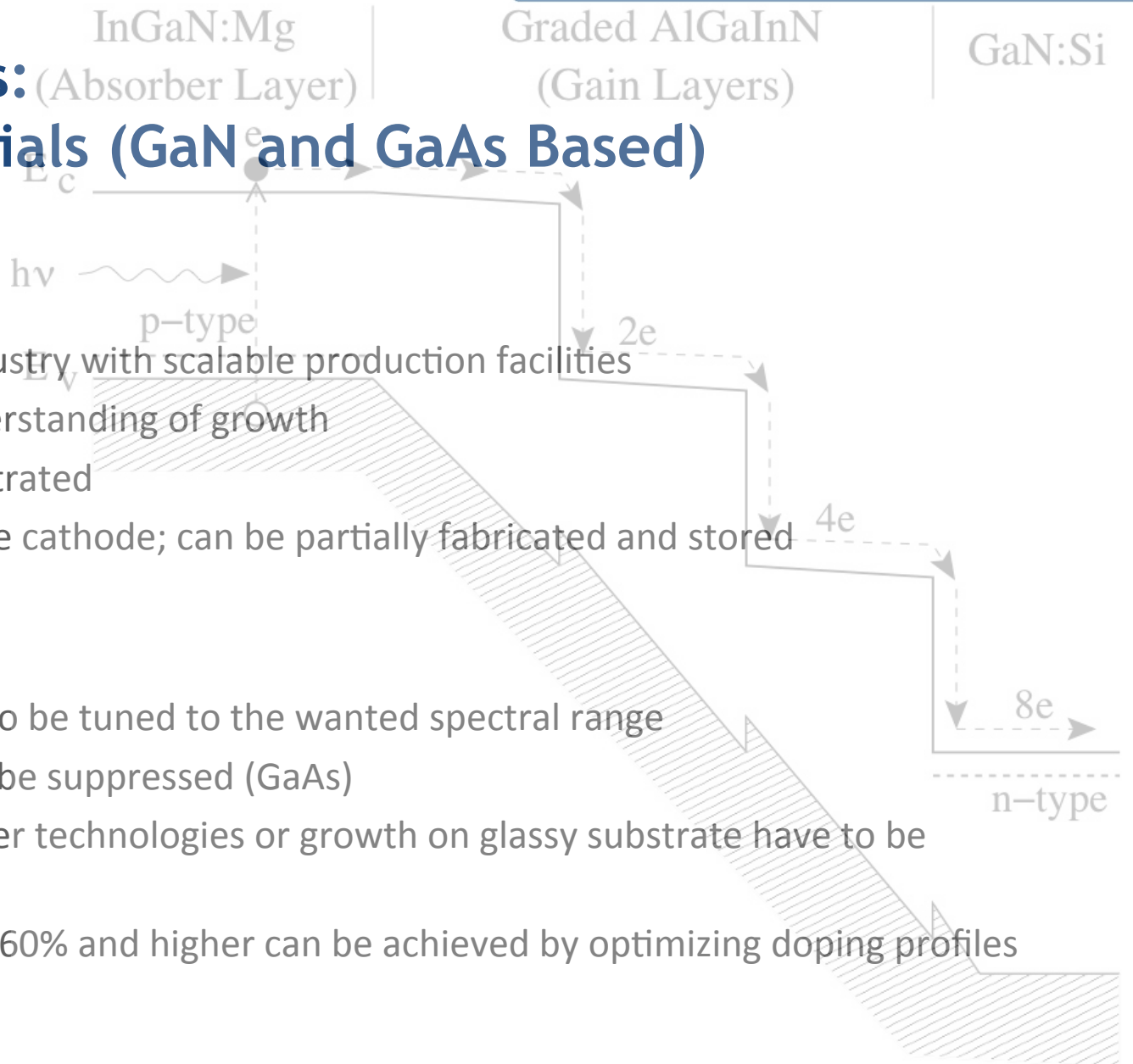
The Challenges: The III-V Materials (GaN and GaAs Based)

The Advantages:

- Well developed industry with scalable production facilities
- Excellent basic understanding of growth
- Good QE is demonstrated
- Very inert and stable cathode; can be partially fabricated and stored

The Problems:

- Light response has to be tuned to the wanted spectral range
- Dark current has to be suppressed (GaAs)
- Cost efficient transfer technologies or growth on glassy substrate have to be developed
- Increasing QE up to 60% and higher can be achieved by optimizing doping profiles



The Challenges: Novel Concepts (Nano Structures and Alternative Processing)

The Advantages:

- Minimizing reflection losses
- Large tunability of materials (band-structure, mechanical properties)
- “natural” protection mechanism against ion-etching
- Conceptual new ways of electron emission enhancement (electric field enhanced)

The Problems:

- Unknown dark current behavior
- Novel technology with limited experiences and industrial facilities
- Many basic and fundamental aspects have to be understood before an industrial production is possible

<http://cgd.eecs.northwestern.edu/research/ebeam.php>

Summary

Status Quo:

- Small numbers of large area photocathode production with sufficient QE was demonstrated (curved surface)
- No 8"x8" flat system was demonstrated
- Currently there is no process available which allows to produce large amounts of these cathodes.

Our Program:

- Rational design or discovery of novel materials guided by basic understanding of functionality: Cross correlating microscopic properties and functionality
- The activities in ANL should be correlated with the requirements of industrial production
- The suggested program includes three areas of activities:
 - Multialkali PC
 - III-V PC (GaAs and GaN)
 - Nano-structured materials